

LIQUIDPREP 800 WITH μ SI

PRODUCT OVERVIEW

PRECISION MEETS AUTOMATION



Trace contamination impacts yield long before it becomes visible in routine analysis. The LiquidPrep 800 with μ SI is designed for reliable, automated liquid process chemical preparation for monitoring at ultra-trace level. It combines clean sample handling, controlled preparation, and coordinated sample introduction in ICP MS system.

ABOUT THE SYSTEM

LIQUID METROLOGY SYSTEMS

PRECISION MEETS AUTOMATION

Sample introduction is a critical step in ultra-trace analysis. The integrated μ SI module helps keep every run controlled, repeatable, and aligned with your ICP-MS workflow.

The LiquidPrep 800 with μ SI is designed for ultra-trace elemental analysis of liquid process chemicals. It combines ultra-clean sample handling, automated multi-point calibration, and active pressure-controlled sample transfer to support reliable results, more consistent quality, and smoother daily operation. The integrated μ SI module connects sample preparation directly with ICP-MS sample introduction, while the dual-loop fluid architecture helps keep your workflow moving by preparing the next sample while the current one is being analyzed. Built for ISO Class 3 cleanroom environments, the system supports safe, efficient, and dependable liquid chemical monitoring.



Fully automated system for sample analysis
with ICPMS calibration and rinse procedures



Auto conditioning for matrix change
ensuring smooth transitions



Ultra-clean automated sample transfer
with dilution and cleaning procedures



Manual sample provision
through vials as an additional flexible option



Dual-loop architecture
Next sample prep while measuring one



Integrated safety system
for autonomous operation

- Incoming chemical inspection for semiconductor manufacturing
- Failure analysis and advanced process monitoring
- Consistent wet-process chemistry monitoring
- Contamination and purity control for OLED and Display manufacturing

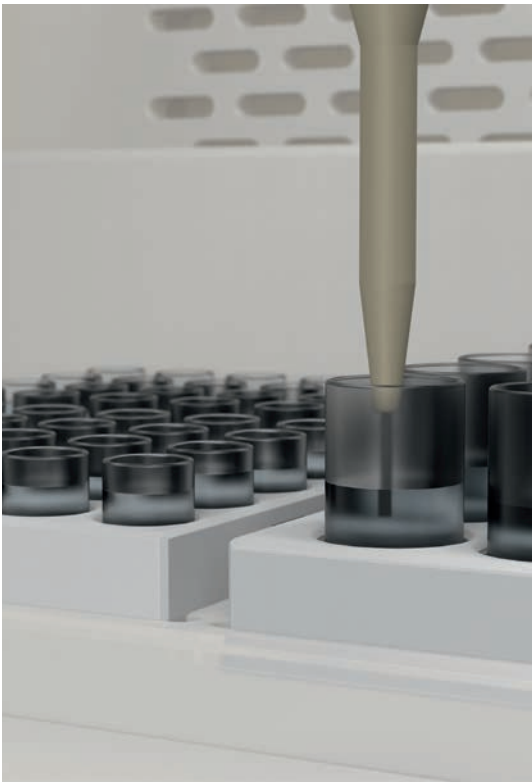
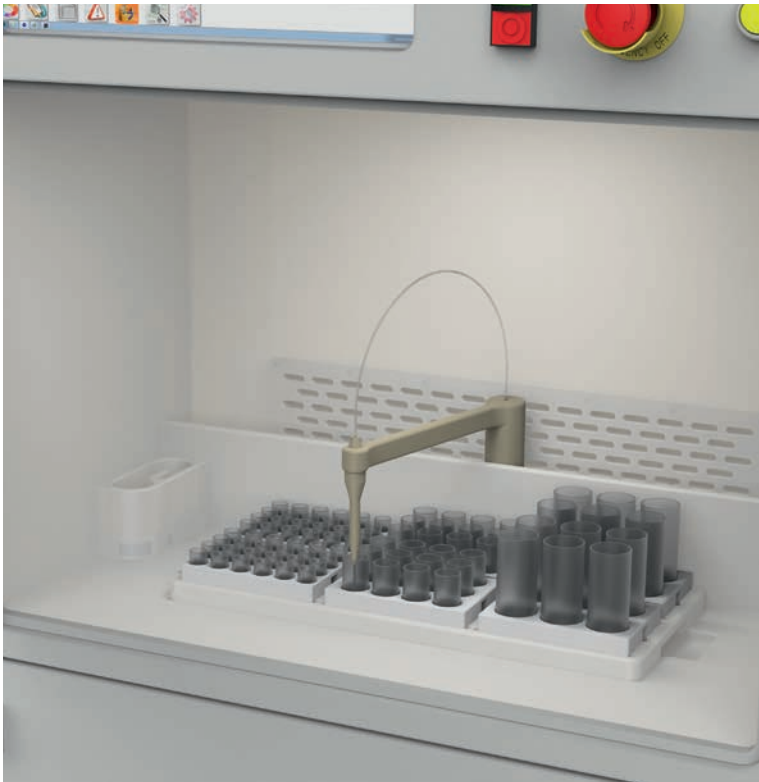


TECHNICAL PARAMETERS

SPECIFICATIONS	
Key Features	- Fully automated ICP-MS sample preparation, calibration, and introduction - Ultra-trace analysis of metallic impurities from ppt to ppq - Integrated μSI module for tightly coordinated sample introduction - Dual-loop fluid architecture for continuous, high-throughput operation - Autonomous operation with integrated safety, CE and SEMI S2 certified
Cleanroom class	ISO 3 or better
Measurement Technology	ICP-MS (Inductively Coupled Plasma Mass Spectrometry)
Sample sizes	500 μ l–500 ml
Chemical scope	HF, HNO ₃ , H ₂ O ₂ , HCl, and other chemicals *
Certifications	CE, SEMI S2
ENVIRONMENTAL	
Utilities	- Compressed Dry Air (required utility) - Ultra-Pure Water supply (< 0.055 μS/cm conductivity) - Fluid drain and acid drain required - Exhaust ($\varnothing$ 50 x 60 mm socket, 200 l/min flow)
Power Requirements	200–230 V AC, 50/60 Hz, 3 A
System Dimensions	654 x 1772 x 555 mm (LxHxD)
System Weight	210 kg
Temperature (rel. Humidity)	18–24 °C (50–60 % non-condensing)

The μ SI module is an integral part of the system. It provides the connectivity and control layer that links the sample preparation workflow to the ICP-MS instrument, enabling coordinated, automated operation.

* For use with other chemicals, please contact the manufacturer.





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